Page 2

Dkt: 884.G23US1

IN THE CLAIMS

Please amend the claims as follows:

- 1. (Currently amended) A method [[of]] comprising:
 - manufacturing a hermetically-sealed optoelectronic package having:
 - an optoelectronic device mounted on a first portion of <u>an upper surface</u> a top <u>surface</u> of an insulating base: [[,]]
 - a metal <u>sealing member</u> layer mounted to a second portion of the <u>upper surface</u> top surface of the insulating base, the second portion surrounding the first portion;[[,,]]
 - and a metal cap coupled to the metal <u>sealing member</u> layer, the method comprising:
 - supplying a force to push the metal cap against the metal sealing member layer;
 - applying a first electrode to the metal cap;
 - applying a second electrode to the metal sealing member layer; and
- supplying a current between the first and second electrodes to weld the metal cap to the metal sealing member layer.
- 2. (Currently amended) The method of claim 1, wherein the second electrode has multiple fingers to make contact with the metal <u>sealing member layer</u> at multiple points.
- 3. (Currently amended) The method of claim 2, wherein the multiple fingers of the second electrode are independently positioned on the metal <u>sealing member layer</u>.
- 4. (Original) The method of claim 2, further comprising:
- independently adjusting one or more currents provided to the multiple fingers of the second electrode.
- 5. (Currently amended) The method of claim 1, wherein the metal cap is coupled to an upper

Page 3

surface of the metal <u>sealing member layer</u> and the second electrode is also coupled to the upper surface of the metal sealing member layer layer.

- 6. (Withdrawn) The method of claim 1, wherein the metal cap is coupled to an upper surface of the metal layer and the second electrode is coupled to a side surface of the metal layer, the side surface being substantially 90 degrees from the upper surface.
- 7. (Withdrawn) The method of claim 1, wherein the metal cap is coupled to an upper surface of the metal layer and the second electrode is coupled to a bottom surface of the metal layer, the bottom surface being substantially 180 degrees from the top surface.
- 8. (Original) The method of claim 1, wherein the second electrode is cone-shaped.
- 9. (Withdrawn) A method for manufacturing an electronic package, comprising: applying a first electrode to a cap;

applying at least one or more second electrodes to a ceramic substrate, wherein the at least one or more second electrodes are applied to at least one or more sidewalls of the ceramic substrate and wherein the ceramic substrate includes a seal disposed on a surface of the ceramic substrate to contact the cap;

contacting the cap with the seal of the ceramic substrate; and

applying a current between said first electrode and said at least one or more second electrodes to weld the cap to the ceramic substrate.

- 10. (Withdrawn) A method as claimed in claim 9, wherein the ceramic substrate is a rectangular structure having at least four sidewalls.
- 11. (Withdrawn) A method as claimed in claim 9, wherein the ceramic substrate has a least one sidewall.
- 12. (Withdrawn) A method as claimed in claim 9, wherein the substrate has at least one curved

Page 4

Dkt: 884.G23US1

sidewall.

13. (Withdrawn) A method as claimed in claim 9, wherein the ceramic substrate includes a

radio-frequency circuit disposed thereon.

14. (Withdrawn) A method as claimed in claim 9, further comprising controlling the current in

individual ones of the at least one or more second electrodes to provide a hermetic seal between

the cap and the ceramic substrate.

15. (Withdrawn) A method as claimed in claim 9, wherein the at least one or more second

electrodes include an insulator to contact a base support during said applying a current.

16. (Withdrawn) A method as claimed in claim 9, wherein the ceramic substrate does not

include filled vias to pass welding current.

17. (Withdrawn) A method as claimed in claim 9, wherein the ceramic substrate is a rectangular

structure having four sidewalls, the at least one or more second electrodes including four second

electrodes to be applied to respective sidewalls of the ceramic substrate.

18. (Withdrawn) A method for manufacturing an electronic package, comprising:

applying a first electrode to a cap;

applying at least one or more second electrodes to an insulator substrate, wherein the at

least one or more second electrodes are applied to at least one or more sidewalls of the insulator

substrate and wherein the insulator substrate includes a seal disposed on a surface of the isolator

substrate to contact the cap;

contacting the cap with the seal of insulator substrate; and

applying a current between said first electrode and said at least one or more second

electrodes to weld the cap to the insulator substrate.

19. (Withdrawn) A method as claimed in claim 18, wherein the insulator substrate has a

Serial Number: 10/732,712

Filing Date: December 11, 2003

Title: METHOD AND APPARATUS FOR MANUFACTURING A TRANSISTOR-OUTLINE (TO) CAN HAVING A CERAMIC HEADER

conductivity of less than 1 (ohm-centimeters)⁻¹.

20. (Withdrawn) A method as claimed in claim 18, wherein the insulator substrate is a rectangular structure having four sidewalls, the at least one or more second electrodes including four second electrodes to be applied to respective sidewalls of the insulator substrate.